

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:)	
)	Examiner:
Yuichiro Nakamura et al.)	
)	Group Art Unit:
Application No.:)	
)	
Corresponding International Filing No.:)	
PCT/JP2005/002209)	
)	
Filed: Herewith)	
)	
For: SPUTTERING TARGET WITH)	
FEW SURFACE DEFECTS, AND)	
SURFACE PROCESSING)	
METHOD THEREOF)	

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SECOND PRELIMINARY AMENDMENT

Sir:

Please amend the above-identified patent application as follows.

Amendments to the Specification begin on page two of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page three of this paper.

Remarks begin on page five of this paper.